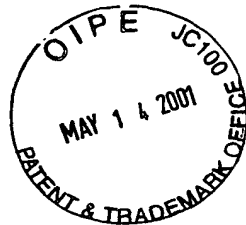


#5 IDS
M. Brunson
5/18/01



XA-9387

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Group Art Unit: 2877

Appln. No.: 09/714,183

Filed: November 17, 2000

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

* * *

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

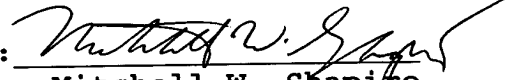
Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

The documents on the attached List are cited in the specification, on pages 2 and 17, and their relevance is addressed therein. Partial translations are also being provided (see the accompanying pages titled "Attached Sheet").

RECEIVED
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TC 2877 MAIL ROOM

Also attached for the Examiner's information is an English translation of the International Preliminary Examination Report from the parent PCT application.

Respectfully submitted,

By: 
Mitchell W. Shapiro
Reg. No. 31,568

MWS:pdh

Miles & Stockbridge P.C.
1751 Pinnacle Drive
Suite 500
McLean, Virginia 22102-3833
(703) 610-8652

May 14, 2001

FORM PTO-1449

Atty. Docket No.

Appln. No.

LIST OF DOCUMENTS CITED BY APPLICANT

XA-9387

09/714,183

Applicant

Hitoshi TAKEUCHI

Filing Date

November 17, 2000

Group

2877

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-Class	Translation
	AL	59-226317	12/19/84	Japan			Partial
	AM						
	AN						
	AO						
	AP						
	AQ						

OTHER (including author, title, date, pertinent pages, etc.)

	AR	Parity, vol. 05, No. 10, 1990-10, pp. 37-39 (with partial translation)
	AS	

Examiner

Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.